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## (54) Positive-tone photoimageable crosslinkable coating

(57) The imaged portion of a positive-tone-photoimageable dielectric coating composition comprising a combination of a novolac resin and a naphthoquinone-diazide is soluble in an aqueous alkaline developer and the developed coating is rendered highly stable, chemically and thermally, by the presence therein of a crosslinkable resin and dicyandiamide or a thermally labile halogen-containing compound as a curing catalyst while heating the coating to cure it.

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## Description

[0001] The present invention is directed to a positive-tone photoimageable dielectric composition which forms the permanent innerlayers of a multilayer printed circuit board, and to a method for forming such a board. It is also directed to a novel method for manufacturing multilayer printed circuit boards by the selective plating of the dielectric layers, eliminating the need for the standard copper foil inner layers, and the photodefinition of vias, thereby eliminating the need for drilled holes in most instances. The invention is also directed to the use of the photoimageable dielectric composition as a solder mask.

## BACKGROUND OF THE INVENTION

[0002] Multilayer printed circuit boards have traditionally comprised a stack of individual printed circuit boards or innerlayers separated by dielectrical material. The circuitry of the several innerlayers is electrically connected by bored and plated-through holes. Multilayer printed circuit boards provide circuitry in a three-dimensional array and are therefor advantageously space-saving, relative to individual printed circuit boards, which provide at most two layers of circuitry on a two-sided board.

[0003] These printed circuit boards are commonly provided with internal ground and power planes. These internal planes are frequently solid sheets of copper interrupted only by clearance holes (the perforations required for electrically isolating the through hole pattern of the printed circuit board). Ground and power planes provide power voltage and current and ground connections for the components of the multilayer printed circuit. A second function of the ground and power planes is to provide electromagnetic shielding for the multilayer printed circuit board and reduce the electromagnetic and radio frequency interference. Multiple ground and power planes and additional ground planes on the surface layers with the conductive pattern are common.

[0004] Multilayer circuits enable formation of multiple circuits in minimal volume. They typically comprise a stack of layers with layers of signal lines (conductors) separated from each other by dielectric layers having plated holes known as vias providing electrical interconnections between the layers.

[0005] Current processes for fabricating multi layer boards are extensions of methods used for fabricating double sided boards. The method comprises fabricating of separate innerlayers having circuit patterns disposed over their surface. A photosensitive material is coated over the copper surfaces of a copper clad innerlayer material, imaged, developed and etched to form a conductor pattern in the copper cladding protected by the photosensitive coating. After etching, the photosensitive coating is stripped from the copper leaving the circuit pattern on the surface of the base material. Following formation of the innerlayers, a multilayer stack is formed by preparing a lay up of innerlayers, ground plane layers, power plane layers, etc., typically separated from each other by a dielectric prepreg (a layer consisting of glass cloth impregnated with partially cured material, typically a B-stage epoxy resin). The outer layers of the stack comprise copper clad glass filled epoxy board material with the copper cladding comprising exterior surfaces of the stack. The stack is laminated to form a monolithic structure using heat and pressure to fully cure the B-stage resin.

[0006] Interconnections or through-holes, buried vias and blind hole interconnections are used to connect circuit layers within a multilayer board. The buried vias are plated through holes connecting two sides of an innerlayer. Blind vias typically pass through one surface of the stack and pass into and stop within the stack. Regardless of the form of interconnections, holes are generally drilled at appropriate locations through the stack, catalyzed by contact with a plating catalyst and metallized, typically with electroless copper overplated with electrolytic copper, to provide electrical contact between circuit innerlayers.

[0007] The uses, advantages and fabricating techniques for the manufacture of multilayer boards are described by Coombs, Printed Circuits Handbook, McGraw Hill Book Company, New York, 2nd edition, pp. 20-3 to 23-19, 1979, incorporated herein by reference.

[0008] Multilayer boards have become increasingly complex. For example, boards for main frame computers may have as many as 36 layers of circuitry, with the complete stack having a thickness of about 1/4 inch. These boards are typically designed with 4 mil wide signal lines and 12 mil diameter vias for interconnections between signal line layers. For increased densification, it is desired to reduce signal lines to a width of 2 mils or less and vias to a diameter of 2 to 5 mil or less.

[0009] The photoimageable dielectric coatings for printed circuit boards on the leading edge of the technology must be capable of being processed in a minimum number of steps. Their dielectric and photolithographic properties, flexibility, and intercoat adhesion also must be excellent. A low photospeed, high moisture resistance, and good adhesion to a plated metal are also important properties of such coatings.

[0010] This invention is directed to positive-tone photosensitive dielectric compositions because of the resolution limitations, limited aspect ratio, limited process latitudes (exposure, development), and the leaching of organics during plating cycles experienced during the use of the typical negative acting photoresists.

[0011] The processing of positive acting photoresists generally follows the sequence of applying a solution of the

resist to a copper foil laminated to an epoxy resin base, drying and baking the resist to expel the solvent, exposing the resist to actinic radiation through a patterned photomask to define an image, dissolving the exposed portions of the resist in an alkaline developer to delineate the image, rinsing, and in some instances post-baking the imaged resist. The areas void of resist, comprised of exposed copper substrate, are then either etched or electroplated. As was said above,

the use of copper foil is eliminated by the method of this invention.

[0012] U.S. Patent No. 4,672,020 (3M) teaches a multilayer dry film photoresist comprising a positive acting photoresist composition comprising an o-quinone diazide in a phenol formaldehyde resin as the binder in the first functional layer. The binder becomes more soluble in an aqueous alkaline solution upon exposure to actinic radiation.

## SUMMARY OF THE INVENTION

[0013] Now we have found that the post-develop image of a positive-tone novolac/diazonaphthoquinone composition may be made highly stable, both chemically and thermally, by the incorporation of crosslinkable resins, such as epoxy resins, and a thermal curing catalyst.

[0014] It is an object of this invention, therefore, to provide a thermally crosslinkable, positive-tone, photoimageable dielectric composition which may be used as a solder mask and as an innerlayer in multilayer printed circuit boards.

[0015] It is a related object of this invention to provide a novel method for manufacturing multilayer printed circuit boards by the selective plating of the dielectric layers, eliminating the need for the standard copper foil inner layers.

[0016] It is another related object of this invention to provide a positive-tone, photoimageable dielectric composition whose post-develop image is highly stable, both chemically and thermally.

[0017] It is still another related object of this invention to provide a multilayer printed circuit board having permanent innerlayers made of a positive-tone photoimaged dielectric composition.

[0018] It is yet another object of this invention to provide a method for making a multilayered printed circuit board by which the vias are photodefined.

[0019] These and other objects of the invention which will become apparent from the following description are achieved by a photoimageable dielectric composition comprising a novolac resin, a crosslinkable resin, a naphthoquinonediazide, and a curing catalyst selected from the group consisting of dicyandiamide and a thermally labile halogen-containing compound, and mixtures thereof.

## DETAILED DESCRIPTION OF THE INVENTION

[0020] To better understand the invention, the following definitions have been adopted:

[0021] Photoimageable dielectric coating means an organic dielectric coating composition capable of imaging by exposure to activating radiation and development to yield a relief image and become an integral part of a multilayer board. It may be applied as a liquid coating composition and dried to a tack free coating or as a dry film. Preferably, the dielectric constant of the coating does not exceed 4.5.

[0022] Imaged opening means a relief image of (1) recesses or channels defining a pattern of conductors or (2) openings for interconnections, within a dielectric coating. Imaged openings are subsequently selectively metallized whereby metal is contained within the recesses of the relief image.

[0023] Substantially means largely if not wholly that which is being specified so that the difference is inconsequential.

[0024] The major portion of the binder for the photoimageable dielectric composition of this invention is the novolac resin, which imparts an aqueous base solubility to the composition and serves as the backbone thereof which reacts with the crosslinkable resins during the thermal crosslinking of the innerlayers. Novolac resins are commonly known products of the acid catalyzed condensation of a phenol and an aldehyde such as formaldehyde, acetaldehyde, and furfural. The term phenol is used herein to mean phenols as a class and includes alkylphenols such as cresol, the xylenols, and butylated phenolic novolacs. Suitably, the amount of the novolac resin may be from about 30 to about 80 % by weight of the total composition, but it is preferred to use from about 45 to 70%, of the novolac in the photoimageable dielectric coating composition of this invention. A preferred photoimageable dielectric coating composition contains about 46 % by weight of the cresol novolac resin. The resins are widely available from many chemical suppliers.

[0025] The amount of crosslinkable resin for curing the novolac resins in the photoimageable dielectric composition to make the innerlayers of the multiple layered printed circuit board of this invention may be from about 5 to about 40 % but it is preferably from about 10 to about 30 and more preferably from about 15 to about 25 % by weight of the total composition. Epoxy resins in general are suitable as such a crosslinking agent for the purposes of this invention. Epoxy novolacs are a particular example of the epoxy resins. A preferable amount of such a multifunctional novolac is from about 5 to about 20 %, more preferably, from about 8 to about 12 %, and still more preferably, about 10 % by weight.

[0026] A photoimageable dielectric composition of this invention may contain about 20 % by weight of an epoxidized polybutadiene sold by Elf Atochem under the trademark POLY bd 605 and having a weight average molecular weight of 3320, a number average molecular weight of 1350, a viscosity of 8000 mPa.s (8000 cps) at 25°C and an epoxy equiv-

alent weight of 310.

[0027] In a preferred photoimageable dielectric coating composition of this invention, a butylated phenolic novolac is used along with an epoxidized novolac resin. The butylated phenolic novolac imparts flexibility to the cured photoimageable dielectric coating of this invention and it imparts a printout image in conjunction with the photoactive diazonaphthoquinone compound. It may be used in amounts of from about 5 to about 30 %, preferably from about 5 to about 20 %, more preferably from about 8 to about 12 %, and still more preferably, about 10 % of the total weight of the coating composition of this invention.

[0028] The naphthoquinonediazide is the photoactive compound which imparts a positive-tone image to the photoimageable dielectric coating of this invention. Examples of the naphthoquinonediazide include, without limitation, naphthoquinone-1,2-diazide-5-sulfochloride, its 4-sulfochloride isomer, and diazoquinone sulfonyl esters of trihydroxy benzophenone. An isomeric mixture of 2,1,5-diazoquinone sulfonyl esters of trihydroxy benzophenone (hereinafter called 215DNQTHB) is available from ChemDesign Corporation of Fitchburg, Massachusetts. Upon irradiation with ultraviolet light such photoactive compounds cause the dielectric coating composition to become soluble in aqueous alkaline solutions. Suitably, from about 5 to about 30 % of the diazonaphthoquinone may be used but it is preferable to use from about 10 to about 20% by weight of the total weight in formulating the photoimageable dielectric coating composition of this invention. A preferred composition contains about 10% of the diazonaphthoquinone compound.

[0029] In this invention, a strong Lewis acid is generated when the thermally labile, halogen-containing curing catalyst is heated in the photoimageable dielectric coating composition, thereby catalyzing the condensation of the novolac resins with the crosslinkable resins therein and thus effecting a cure of the imaged innerlayer without the need for an ultraviolet radiation curing step. The thermally labile, halogen-containing curing catalyst is exemplified by diaryliodonium hexafluorantimonate (or DAI HFA); tribromomethylphenyl sulfone; trichloroacetamide; bis-chloroimidazole; 2,4-bis(trichloromethyl)-6-(4'-methoxyphenyl)-s-triazine; 2,4-bis-(trichloromethyl)-6-(4'-methoxynaphthyl)-s-triazine; 2,4-bis-(trichloromethyl)-6-piperonyl-s-triazine; 2,4-bis-(trichloromethyl)-6-(4'-methoxystyryl)-s-triazine; 2[2'(5"-methylfuryl)ethylidene]-4,6-bis(trichloromethyl)-s-triazine; 2[2'-furyl(ethylidene)-4,6-bis(trichloromethyl)-s-triazine; 2(2',-methyl-4'-diethylaminostyryl)-4,6-bis(trichloromethyl)-s-triazine; 2(2'-trimethylammonium ethylamino)-4,6-bis-(trichloromethyl)-s-triazine; 2(3', 4'-dimethoxystyryl)-4,6-bis(trichloromethyl)-s-triazine; and 5,7-bis(tribromomethyl)-s-triazoro[1,5-a]pyrimidine; all of which are commercially available. Diaryliodonium hexafluorantimonate is sold under the trademark SarCat as a cationic photoinitiator by the Sartomer Company, Inc. The Sar-Cat CD-1012 product is distinguished by a hydroxymyristyloxy group attached to one of two phenyl groups. We have found that low levels, on the order of from about 0.1 to about 2 % by weight, of the thermal curing catalyst are effective in the curing of the coating without substantially impeding the dissolution of the coating to yield a positive image but that higher levels yield a negative tone image. The amount of such an acid generating catalyst is preferably from about 0.5 to about 1.5 % and more preferably from about 1 to about 1.5 % by weight of the total weight of the photoimageable dielectric coating composition of this invention.

[0030] From about 0.1 to about 2 % by weight of dicyandiamide, based on the total weight of the composition, is suitable as a curing catalyst in the photoimageable dielectric coating composition of this invention. The ratio of the dicyandiamide to the thermally labile catalyst in mixtures thereof is from 1:99 to 99:1, by weight.

[0031] Melamine and oligomers and polymers thereof such as the melamine-formaldehyde resins as well as benzoguanamine-formaldehyde resins, urea-formaldehyde resins, and glycoluril-formaldehyde resins and combinations of said resins are also suitable as crosslinkers for the purposes of this invention. The melamine, benzoguanamine, and glycoluril resins are available under the trademark CYMEL and the urea resins are available under the trademark BEE-TLE. From about 5 to about 30 weight percent of the total solids in the composition is suitable.

[0032] Fillers may be used in amounts of from about 2 to about 40 % by weight of the total composition in order to control the flow of resins therein while the composition is being cured at elevated temperatures. Fumed silica such as that sold under the trademarks CAB-O-SIL and SYLOID is an example of a useful filler. The CAB-O-SIL M-5 silica is particularly useful. Aluminum oxide, exemplified by Degussa's Aluminum Oxide C, may be used at levels of about 30 % by weight as a flow control aid as well as to improve the resistance of the dielectric to permanganate during swell and etch processing. A quartz and kaolinite mixture sold under the trademark SILLITIN by Hoffman is useful in this invention to improve the adhesion of the dielectric to copper. Silanes and titanates may be used in coupling the fillers with the polymeric matrix and beneficially affect the rheology of the dielectric composition.

[0033] A leveling agent such as those sold under the trademark MODAFLOW in the amount of from about 0.2 to about 3 % by weight of the composition of this invention is also useful. A flexibilizing agent such as a poly(vinylmethyl ether) sold under the trademark LUTANOL M-40 is particularly useful in the preparation of a dry film of this invention. An effective amount of the flexibilizing agent is from about 10 to about 40 percent by weight of the total composition.

[0034] The dielectric constant of the photoimageable dielectric coating composition of this invention preferably is not greater than 4.5 and more preferably is not greater than 3.5. The resolution is preferably sufficient to provide line widths of 10 mils or less, more preferably 5 mils or less, and still more preferably about 2 mils or less.

[0035] The photoimageable dielectric coating composition of this invention may be applied to a substrate as a liquid,

then dried, imaged by exposure to UV light and development, and cured or it may be cast as a dry film for storage and subsequent lamination onto a substrate for imaging and curing. The liquid coating composition may be coated onto the surface of a substrate in a variety of ways, including screening, roller coating, curtain coating, and spray coating. A water miscible solvent such as propylene glycol methyl ether acetate may be used in amounts necessary to adjust the viscosity of the photoimageable dielectric coating compositions of this invention to suit the coating method and coating thickness desired. The dielectric substrate for the printed circuit board use may be, for example, a glass-epoxy construction or a polyimide. The coating is tack dried at about 90°C for about 30 minutes and then irradiated through a mask in an image pattern by ultraviolet light having a wave length in the range of from 350 to 450 nm. The total dosage of UV light is from 100 to 800 mJ/cm<sup>2</sup>. The exposed coating is then developed in a 0.17 to 0.3 normal aqueous solution of sodium hydroxide at from 80 to 100° F, rinsed, and cured at a temperature of from 140 to 175° C. for about one hour.

[0036] The developer is a strongly basic solution but it may contain sodium carbonate as well as the hydroxide. Sodium metasilicate and trisodium phosphate are also suitable for use in developing solutions. Surfactants are useful in the developer to assist in the removal of the desired portion of the photoimageable dielectric imagewise. The surfactant may be anionic, cationic, non-ionic, or amphoteric.

[0037] Dry film may be made by drawing down the liquid coating composition with a Baker bar at a setting of from about 4 to about 20 and drying it in a convection oven or tunnel dryer for about 2 to about 60 minutes at from about 35 to about 105° C to obtain films ranging from about 0.5 mil to about 3 mils thick. The dry film may then be laminated onto a dielectric substrate such as a polyimide film or an epoxy resin impregnated glass fiber board at room temperature or at an elevated temperature, e.g., 180° F (82° C). A Hot Roll (DYNACHEM Model 300 or 360) laminator may be used at a speed of 1 to 5 feet per minute, a roll pressure of 40 to 60 psi (0.28-0.41 MPa), and a roll temperature of 225 to 300° F (107-150° C). Vacuum laminators, such as models 724 and 730 sold by Morton International, Inc. may be used, also. In conventional vacuum lamination, in addition to heat and vacuum, mechanical pressure is brought to bear against the dry film. In what is known as a "slap down" process, a rubber blanket is used to press the dry film against the substrate. During vacuum lamination, the photoimageable dielectric dry film is heated to a board surface temperature of 55-90°C with a cycle time of 30-90 seconds and a slap down cycle of 4-12 seconds. A post lamination bake may last for about 30 minutes at about 90° C (194° F) but it may be eliminated under certain conditions. The laminate is then irradiated through a mask in an image pattern by ultraviolet light and developed as described above.

[0038] High resolution relief images including openings that are approximately equal to the thickness of the coating may thus be achieved. By use of such coatings, imaged openings for interconnections and conductors can be of a size equivalent to the resolution capability of the dielectric coating and the method of imaging and may be in any desired shape.

[0039] Adhesion of metal to the dielectric coating may be enhanced by a permanganate process which includes a conditioning step (also known as solvent swell), an etching step, and a neutralizing step. The conditioner may be a mixture of diethylene glycol butyl ether, phosphoric acid, surfactant, and water. Suitable conditioners are available under the trademarks COPPERMERSE M3 and CIRCUPOSIT MLB 211. Suitable potassium permanganate etching solutions are available under the trademarks COPPERMERSE M4 and CIRCUPOSIT MLB 213. Suitable neutralizers are sold under the trademarks COPPERMERSE M6 and CIRCUPOSIT MLB 216. The COPPERMERSE products are sold by LeaRon, Inc. The CIRCUPOSIT products are sold by Shipley Co.

[0040] Selective metal deposition in the imaged openings may be performed in a conventional manner. It is characterized by the selective metallization of the relief image of the dielectric coating without an increase in the surface resistivity of an underlying substrate between conductor lines. Plating can occur only on those areas where the resist has been removed (additive production of the circuits), or on the entire surface including areas where the resist was removed by development as well as upon the resist itself (subtractive production of the circuits) or some degree of plating falling between these extremes (semi-additive production of the circuits). For a discussion of the specifics of circuitry and interconnect creation see U.S. Pat. No. 4,847,114 (Brach et al).

[0041] It is preferred for adhesion enhancement to bake after electroless metal deposition and after subsequent build up metallization processes at 145°C-160°C for 30 to 60 minutes

[0042] If the additive process is chosen, then plating will occur in those areas where the photoimageable dielectric coating has been removed by development and upon the surface of the dielectric in a defined manner such that defined circuitry and interconnects are created. Thus, the plating itself will define the circuitry and other features desired. In the additive process, the photoimaging of the permanent dielectric will create and define the circuitry and other surface features desired as well as the holes and vias which will interconnect the various layers of the circuitry package.

[0043] If the substrate to be coated is a circuit, the process may comprise formation of a dielectric coating over a circuit with imaged openings defining interconnections. The walls of the imaged openings in the dielectric coatings contain metal as it deposits during plating and assures a desired cross sectional shape of the deposit. The process is repeated sequentially to form sequential layers of circuits and interconnections.

[0044] In the subtractive procedure, the entire surface will be plated. The circuitry and other features will be defined by subsequent etching of the plated metal. In the subtractive manner, the photodefinition of the permanent resist will

typically be used for the creation of holes and vias which connect the various layers of the circuitry package, thus eliminating the need for drilling holes.

[0045] The lines, holes and vias may be made conductive by filling with a conductive paste as an alternative to plating.

[0046] The plating solution is typically an electroless copper plating solution well known in the art and typically comprises a source of cupric ions, a complexing agent to hold the ions in solution, a reducing agent to reduce the cupric ions to metallic copper in the presence of the catalyst-e.g., formaldehyde and a pH adjustor. Typical copper plating solutions are disclosed in U.S. Patent Nos. 4,834,796; 4,814,009; 4,684,440; and 4,548,644.

[0047] The coating composition and process of this invention are further described in the following examples, which are not limiting in any way. All parts are by weight unless otherwise indicated and all components are 100 % solids unless otherwise indicated.

#### EXAMPLE 1

[0048] The following composition was prepared:

Component	Wt. % solids
Cresol novolac (Schenectady Resins HRJ10805)	50.1
Epoxy novolac (EPON 164)	4.9
Epoxidized polybutadiene (POLY BD 605)	19.8
Butylated novolac (SANTOLINK 560)	14.3
Diazonaphthoquinone sulfonate of 2,1,5-trihydroxybenzophenone	9.9
DAI HFA (CD-1012)	1.0
	100.0
Filler	Wt % of total solids above
Silica (SYLOID 7000)	5.0
Solvent	Wt % of total composition
Propylene glycol methylether acetate	46-48

[0049] The coating composition was mixed thoroughly and applied to a glass/epoxy laminate by a wire wound draw-down bar to a dry thickness of 1-2 mils. The coating was then dried at 90° C (194° F) for 30 minutes and exposed image-wise to patterned actinic radiation from a broad band mercury vapor lamp (ORC HMW201B). The total radiation dosage was about 400 mJ/cm<sup>2</sup>. The exposed surface was then immersed in an aqueous 0.2 N solution of sodium hydroxide at 95° F for about 2 minutes, thereby selectively removing the exposed portions of the coating. The developed coating was cured at 311° F (155° C) for one hour followed by treatment in a conventional permanganate process.

#### EXAMPLE 2

[0050] A photoimageable dielectric coating composition of this invention is made according to the following formulation:

Component	Wt % solids
Cresol novolac resin	46.0
Epoxidized polybutadiene	20.0

(continued)

Component	Wt % solids
Epoxidized novolac resin	10.0
Butylated novolac resin	10.0
Diazonaphthoquinone sulfonate of 2,1,5-trihydroxybenzophenone	10.0
DAI-HFA (CD-1012)	1.0
Leveling agent	0.2
Fillers, colorants, additives	2.8

[0051] A solution similar to that of Example 1 is coated on each of six of the epoxy/glass laminates and then dried, irradiated, developed and cured as in that example to give six innerlayers suitable for electroless plating and assembly with compression into a multilayered printed circuit board of this invention.

**EXAMPLE 3**

[0052] The following composition was prepared:

Component	Wt. % solids
Cresol novolac (Schenectady Resins HRJ10805)	60.0
Epoxy novolac (EPON 164)	10.0
Butylated novolac (SANTOLINK 560)	15.0
Diazonaphthoquinone sulfonate of 2,1,5-trihydroxybenzophenone	12.5
DAI HFA (CD-1012)	1.0
Leveling agent (Modaflow)	1.5
	<u>100.0</u>
Filler	Wt % of total solids above
Silica (CAB-O-SIL M5)	8.0
Solvent	Wt % of total composition
Propylene glycol methylether acetate	47.4

[0053] The coating composition was mixed thoroughly and applied to a glass/epoxy laminate by a wire wound draw-down bar to a dry thickness of 1-2 mils. The coating was then dried at 90° C (194° F) for 30 minutes and exposed image-wise to patterned actinic radiation from a broad band mercury vapor lamp (ORC HMW201B). The total radiation dosage was about 400 mJ/cm<sup>2</sup>. The exposed surface was then immersed in an aqueous 0.25 N solution of sodium hydroxide at 86° F for about 2 minutes, thereby selectively removing the exposed portions of the coating. The developed coating was cured at 311° F (155° C) for one hour. The coating survived three successive 5-minute immersions of a conventional permanganate process. This composition afforded better resolution and a better sidewall profile than that of Example 1.

**EXAMPLES 4-16**

[0054] The following compositions were prepared:

Component	Wt. % solids
Cresol novolac (Schenectady Resins HRJ10805)	53.8
Epoxy novolac (EPON 164)	9.0
Butylated novolac (SANTOLINK 560)	15.31
Diazonaphthoquinone sulfonate of 2,1,5-trihydroxybenzophenone	12.5
DAI HFA (CD-1012)	0.9
FLEXO Blue dye 680 (BASF)	0.23
Silane (Höls IMEO)	0.41
Leveling agent (Modaflow)	1.5
CYMEL melamine resin (as indicated in Table 1)	10.00
	<u>100.00</u>
Filler	Wt % of total solids above
Silica (CAB-O-SIL M5)	9.0
Solvent	Wt % of total composition
Propylene glycol methylether acetate	46-48

[0055] Each coating composition was mixed thoroughly and applied to a glass/epoxy laminate by a wire wound draw-down bar to a dry thickness of about 35 microns. The coating was then dried at 100° C for 30 minutes and exposed imagewise to patterned actinic radiation from a broad band mercury vapor lamp (ORC HMW201B). The total radiation dosage was about 500 mJ/cm<sup>2</sup>. The exposed surface was then immersed in an aqueous 0.25 N solution of sodium hydroxide at 86° F for about 2 minutes, thereby selectively removing the exposed portions of the coating. The developed coating was cured at 155° C for one hour. The develop breakpoint, the Stouffer 21 step value, and the pencil hardness (PH) of the photoresist are shown in Table 1.

TABLE 1

Example	Resin	Dev.brkpt(sec)	Stouffer	P H
4	1161	39	2	2H
5	1125	77	2	6H
6	1158	92	1	5H
7	1170	42	2	2H
8	1156	73	1	5H
9	1123	49	2	5H
10	1171	15	5	2H
11	1130	49	2	5H
12	1141	95	1	2H
13	380	42	2	2H
14	325	48	2	5H
15	303	33	2	5H



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TABLE 1 (continued)

Example	Resin	Dev.brkpt(sec)	Stouffer	P H
16	300	28	3	5H

## EXAMPLES 17-18

[0056] The following compositions were prepared:

Component	Wt. % solids
Cresol novolac (Schenectady Resins HRJ10805)	53.8
Epoxy novolac (EPON 164)	9.0
Butylated novolac (SANTOLINK 560)	15.31
Diazonaphthoquinone sulfonate of 2,1,5-trihydroxybenzophenone	12.5
DAI HFA (CD-1012)	0.9
FLEXO Blue dye 680(BASF)	0.23
Silane (Hüls IMEO)	0.41
Leveling agent (Modaflow)	1.5
Urea resin (as indicated in Table 2)	10.00
	100.00
Filler	Wt % of total solids above
Silica (CAB-O-SIL M5)	9.0
Solvent	Wt % of total composition
Propylene glycol methylether acetate	46-48

[0057] Each coating composition was mixed thoroughly and applied to a glass/epoxy laminate by a wire wound draw-down bar to a dry thickness of about 35 microns. The coating was then dried at 100° C for 30 minutes and exposed imagewise to patterned actinic radiation from a broad band mercury vapor lamp (ORC HMW201B). The total radiation dosage was about 500 mj/cm<sup>2</sup>. The exposed surface was then immersed in an aqueous 0.25 N solution of sodium hydroxide at 86° F for about 2 minutes, thereby selectively removing the exposed portions of the coating. The developed coating was cured at 155° C for one hour. The develop breakpoint, the Stouffer 21 step value, and the pencil hardness (PH) of the photoresist are shown in Table 2.

TABLE 2

Example	Resin	Dev.brkpt(sec)	Stouffer	P H
17	BEETLE 80	66	1	2H
18	BEETLE 65	20	4	2H

## EXAMPLE 19

[0058] The following composition was prepared:

Component	Wt. % solids
Cresol novolac (Schenectady Resins HRJ10805)	60.25
Epoxy novolac (EPON 164)	10.0
Butylated novolac (SANTOLINK 560)	17.0
Diazonaphthoquinone sulfonate of 2,1,5-trihydroxybenzophenone	10.0
Dicyandiamide	1.0
Blue 680 dye (BASF)	0.25
Leveling agent (Modaflow)	1.5
	<u>100.00</u>
Filler	Wt % of total solids above
Silica (CAB-O-SIL M5)	8.0
Solvent	Wt % of total composition
Propylene glycol methylether acetate	46-48

[0059] Each coating composition was mixed thoroughly and applied to a glass/epoxy laminate by a wire wound draw-down bar to a dry thickness of about 35 microns. The coating was then dried at 100° C for 30 minutes and exposed imagewise to patterned actinic radiation from a broad band mercury vapor lamp (ORC HMW201B). The total radiation dosage was about 500 mJ/cm<sup>2</sup>. The exposed surface was then immersed in an aqueous 0.24 N solution of sodium hydroxide at 86° F for about 2 minutes, thereby selectively removing the exposed portions of the coating. The developed coating was cured at 155° C for one hour. An image was developed in 26 seconds and the film had a pencil hardness of 2H.

#### EXAMPLE 20

[0060] A coating composition having the formulation of Example 19, except for the replacement of half of the dicyandiamide with the DAI-HFA catalyst, is mixed thoroughly and screen printed onto a circuitized glass/epoxy laminate to a dry thickness of about 35 microns. The coating is then dried at 100° C for 30 minutes and the desired pattern of holes and vias is created on the coating by exposure to patterned actinic radiation and development in an aqueous 0.24 N solution of sodium hydroxide at 86° F for about 2 minutes. After curing at 155° C for one hour, a thin conductive layer of copper is deposited on the coated laminate and in the holes and vias by a permanganate process and electroless copper plating. A Laminar HG plating resist film is placed on the thin copper layer and the pattern of the desired circuitry is created on the resist by exposure to patterned actinic radiation and development in an aqueous solution of sodium hydroxide. The exposed thin layer of electroless copper is electroplated to create the circuitry, the residual plating resist is stripped away and the underlying electroless copper is etched away in a sodium persulfate bath. The procedure is repeated sequentially to form multiple layers of circuits and connections.

#### Example 21

[0061] The photoimageable dielectric coating composition of Example 1 is mixed thoroughly and applied to a copper foil to a thickness of 42 microns. The coating is dried at 90°C for 30 minutes and the desired pattern of holes and vias is created on the coating by exposure to patterned actinic radiation and development in an aqueous 0.2N solution of sodium hydroxide at 95°F for about 2 minutes. After curing the coating at 120°C for one hour, the uncoated side of the copper foil is laminated with a protective coating to prevent plating on the copper surface as the holes and vias are electroplated with copper and planarized. The protective coating is removed and the copper foil with the plated vias and holes is hot press laminated at 185°C (365°F) for one hour with a treated copper foil to provide a double-sided copper-

clad board with vias formed between the copper layers. The board is then laminated on both sides with a LAMINAR AT photoresist. Each side is exposed imagewise to actinic radiation and developed to form the image of the desired circuitry. The exposed copper surface is then etched in a cupric chloride etchant to provide circuitry and capture pads to the underlying vias.

#### Example 22

[0062] The coating composition of Example 1 is mixed thoroughly and applied to a copper foil to thickness of about 42 microns. The coating is dried at 90°C for 30 minutes and the desired pattern of holes and vias is created on the coating by exposure to patterned actinic radiation and development in 0.2N aqueous solution of sodium hydroxide at 95°F for about 2 minutes. After curing the coating at 175°C (347°F) for one hour, the uncoated side of the copper foil is laminated with a protective coating to prevent plating the copper surface. The vias and holes are electroplated with copper and subsequently planarized. The protective coating is removed and the photodielectric is treated through permanganate and electroless copper processes. The copper foil is coated with a LAMINAR AT photoresist and the electroless copper on the photodielectric is electroplated to provide a double-sided copper-clad board with vias formed between the copper layers. The exposed copper layers are laminated with a LAMINAR AT photoresist. The photoresists are then exposed imagewise to actinic radiation and developed to form the image of a desired circuitry. The exposed copper surfaces are etched in a cupric chloride etchant to provide circuitry and capture pads to the underlying vias.

#### Example 23

[0063] The coating composition of Example 1 is mixed thoroughly and applied to a copper foil to a thickness of about 42 microns and dried at 90°C for about 30 minutes. A circuitized substrate is coated with a liquid, non-photoimageable dielectric, dried and planarized. The copper-clad photoimageable dielectric is hot roll laminated onto the circuitized board. The bare copper is then coated with a positive-acting photoresist, exposed to actinic radiation in the desired pattern of vias and holes and developed. The exposed copper is etched in cupric chloride. The board is flood exposed with ultraviolet light and developed in 0.20N aqueous sodium hydroxide solution to remove the photoresist coating from the desired vias and holes in the dielectric. After curing the coating at 175°C for one hour, the vias and holes are metallized in an electroless copper process and subsequently electroplated with copper. The bare copper is laminated with LAMINAR AT photoresist which is then exposed imagewise to actinic radiation and developed to form the image of the desired circuitry. The exposed copper surface is then etched in a cupric chloride etchant to provide circuitry.

#### Claims

1. A positive-tone photoimageable dielectric coating composition comprising a novolac resin, a crosslinkable resin, a naphthoquinonediazide, and a curing catalyst comprising dicyandiamide and/or a thermally labile halogen-containing compound.
2. A dielectric coating composition according to claim 1 wherein the novolac resin is from 30 to 80 % by weight of the total composition.
3. A dielectric coating composition according to claim 2 comprising, by weight, from 45 to 70 % of a novolac resin.
4. A dielectric coating composition according to any preceding claim wherein the novolac resin is a cresol novolac resin.
5. A dielectric coating composition according to any preceding claim wherein the crosslinkable resin is an epoxy resin and the amount of the crosslinkable resin is from 5 to 50 % by weight of the total composition.
6. A dielectric coating composition according to any preceding claim wherein the amount of the crosslinkable resin is from 5 to 40 %, preferably 5 to 30 %, by weight of the total solids in the composition.
7. A dielectric coating composition according to any preceding claim wherein the crosslinkable resin is a melamine-formaldehyde resin.
8. A dielectric coating composition according to any one of claims 1 to 6 wherein the crosslinkable resin is a urea-formaldehyde resin.

9. A dielectric coating composition according to any one of claims 1 to 6 wherein the crosslinkable resin is an epoxidized polybutadiene.
10. A dielectric coating composition according to claim 9 wherein the epoxidized polybutadiene constitutes from 15 to 25 % by weight.
11. A dielectric coating composition according to any preceding claim wherein the naphthoquinonediazide is from 5 to 30 % by weight of the total composition.
12. A dielectric coating composition according to any preceding claim wherein the curing catalyst is dicyandiamide, in an amount from 0.1 to 2 % by weight of the total composition.
13. A dielectric coating composition according to any one of claims 1 to 11 wherein the amount of curing catalyst is from 0.1 to 2 % by weight of the total composition, and the curing catalyst is selected from diaryliodonium hexafluoroantimonate; tribromomethyl-phenylsulfone; trichloroacetamide; bis-chloroimidazole; 2,4-bis(trichloromethyl)-6-(4'-methoxyphenyl)-S-triazine; 2,4-bis-(trichloromethyl)-6-(4'-methoxynaphthyl)-S-triazine; 2,4-bis-(trichloromethyl)-6-piperonyl-S-triazine; 2,4-bis-(trichloromethyl)-6-(4'-methoxystyryl)-S-triazine; 2 [2'(5"-methytfuryl)ethylidene]-4,6-bis(trichloromethyl)-S-triazine; 2(2'-furylethylidene)-4,6-bis(trichloromethyl)-S-triazine; 2(2'-methyl-4'-diethylaminostyryl)-4,6-bis(trichloromethyl)-S-triazine; 2(2'-trimethylammonium ethylamino)-4,6-bis-(trichloromethyl)-S-triazine; 2(3',4'-dimethoxystyryl)-4,6-bis(trichloromethyl)-S-triazine; and 5,7-bis(tribromomethyl)-S-triazoro[1,5-a]pyrimidine; and mixtures of said thermally labile compounds.
14. A dielectric coating composition according to claim 13 wherein the curing catalyst is diaryliodonium hexafluoroantimonate.
15. A dielectric coating composition according to claim 1, comprising about 46% of a cresol novolac resin, about 20% of epoxydized polybutadiene, from 8 to 12% of an epoxidized novolac, from 8 to 12% of a butylated phenolic novolac, and from 0.5 to 1.5 % by weight of a diaryliodonium hexafluoroantimonate.
16. A dielectric coating composition according to claim 15 comprising about 10% of the naphthoquinonediazide and about 1% of diaryliodonium hexafluoroantimonate.
17. A positive-tone photoimaged dielectric innerlayer for a printed circuit board, formed by curing a layer of a dielectric coating composition according to any preceding claim.
18. A positive-tone photoimaged dielectric innerlayer for a multiple layered printed circuit board, said innerlayer comprising a cured mixture of a novolac resin, a crosslinking resin, and dicyandiamide or the products of a thermal decomposition of a thermally labile halogen-containing curing catalyst.
19. A multilayered printed circuit board comprising a plurality of positive-tone photoimaged dielectric innerlayers according to claim 17 or claim 18, each of said photoimaged innerlayers defining conductive lines, holes and/or vias.



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# EUROPEAN SEARCH REPORT

Application Number  
EP 98 30 6178

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EPO FORM 1503 (03.02) (P4/C01)



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Application Number  
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